

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of : **Attn: APPLICATION BRANCH**
Norio KIMURA et al. : Attorney Docket No. 2004_0201
Serial No. NEW :
Filed February 25, 2004 :

POLISHING APPARATUS AND METHOD
(Rule 1.53(b) Divisional
of Serial No. 09/824,644,
Filed April 4, 2001)

THE COMMISSIONER IS AUTHORIZED
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CLAIM OF PRIORITY UNDER 35 USC 119

Commissioner for Patents
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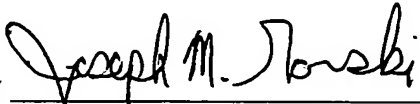
Sir:

Applicants in the above-entitled application hereby claim the date of priority under the International Convention of Japanese Patent Application No. 2000-102669, filed April 4, 2000, and Japanese Patent Application No. 2000-163082, filed May 31, 2000, as acknowledged in the Declaration of this application.

Certified copies of said Japanese Patent Applications are of record in parent application Serial No. 09/824,644, filed April 4, 2001.

Respectfully submitted,

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